Direct Coupling of SiPMs to Scintillator Tiles: Timing and Uniformity

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Max-Planck-Institut für Physik (Werner-Heisenberg-Institut)







SiPMs and Scintillator Tiles

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- Tile Modification

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- - Determination of the Tile (Non-)Uniformity
- - Optimization of the Scintillator Tile Geometry

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1 Motivation: Reasons for Direct Coupling

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Timing of the Tile Signal

Determination of the Tile (Non-)Uniformity







The CALICE Analog Hadron Calorimeter (AHCAL)

SiPMs and Scintillator Tiles

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- Summary

Development of blue sensitive SiPMs

allow for photon readout without wavelength shifting fiber:

- Advantage: Avoid machining of WLS into millions of tiles (ILD) Avoid difficult alignment of SiPM to WLS-end Improve timing of light collection
- Non-uniform cell readout: Measured energy deposition varies with the lateral position at which a particle traverses the tile
- Position dependence affects the performance of the HCAL







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The Effect of Non-Uniform Cell Readout

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Consequences: Subject of further investigations

Consequence 1

Distortion of the cell signal distribution

 \Rightarrow Effect on HCAL calibration

Consequence 2

Distortion of the energy sum distribution of showers \Rightarrow Effect on energy reconstruction process

Consequence 3

Deterioration of the energy resolution increasing with the particle energy



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The Experimental Setup

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Test Stand Properties

- Radioactive ${}^{90}Sr$ source: Beta decay ($E_{end point} = 2.27 \text{ MeV}$)
- $\bullet\,$ Movable stage: Translation in XY-direction over $3\times3\,cm^2$ tile
- Active (Fan, Air Cond.) and Passive (Thermistor) T-control
- $\bullet\,$ Select tile traversing electrons $\rightarrow\,$ Active coincidence trigger



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Time Resolved Measurements

SiPMs and Scintillator Tiles

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Fast timing of HCAL implies fast light collection within tiles

- Aquire waveforms of SiPM Signal with 4 GHz Oscilloscope
- High sampling: Arrival of every single photon on SiPM can be identified



Direct Coupling

Signal from directly coupled tile significantly faster: No delay due to absorption and reemission in WLS fiber



Time Resolved Measurements

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CALICE 1st generation tile with WLS fiber

- Broad signal peak
- Long integration times needed

Directly Coupled Tile

- Fast peaking signal, pronounced peak
- Short integration times sufficient



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• First test: Direct SiPM coupling to one side of a $3 \times 3 \text{ cm}^2$ tile

• Recording of 500 e^- signals at 60 × 60 XY-positions on the tile \rightarrow Pixel Size: 0.5 × 0.5 mm²

• Determine mean signal height (MSH) from signal distribution

MSH vs. XY-Position: Observe strong non-uniformity

Modification of the tile geometry necessary to restore uniformity



Scanning Sequence



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SIPM

Scanning Sequence





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5 Optimization of the Scintillator Tile Geometry





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Tile Development

Simple Tile: SiPM coupled to the side

Highly non-uniform

 \Rightarrow Solution: Reduce scintillating material close to SiPM Overall mean of signal height: 13.0 p.e.

 \Rightarrow Solution: Integrate SiPM into the tile



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Tile Development

Integrated Dimple: Height 1 mm, Width 4 mm, Depth 5.5 mm

- \Rightarrow Overall mean: 18.4 p.e. (Diffuse light refraction at dimple)
- \Rightarrow Good uniformity
- \Rightarrow Signal at SiPM position not lower than 13 p.e.
- \Rightarrow Scalable solution for mass production
- (arXiv:1001.4665 [physics.ins-det])



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Tile Development

Transferable concept for the next generation prototype: 3mm Option: \Rightarrow Overall mean: 13.15 p.e.

 \Rightarrow Signal at Dimple not lower than 8 p.e.



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Tile Development

Very small packaging of new MPPCs

 \rightarrow opens up the possibility for new tile geometries:

Aim: Avoid Signal Drop at SiPM Coupling Position

 \rightarrow Very small integration hole

 \rightarrow 2 mm deep bottom dimple(spherical drilling head with 5 mm radius) Note: Only tested for 5 mm tiles, SiPM is SMD



High Precision Uniformity: Side Coupling vs. Integrated Dimple Concept

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Side Coupling

Part of the Scin- tillator Tile	Deviation of overall mean: 13.0
98% (91%)	±20%
94% (81%)	±10%
69% (57%)	± 5%

 $\mathsf{Unprecise} \to \mathsf{Cut} \; \mathsf{Tile} \; \mathsf{Edges!}$





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Side Dimple

Part of the Scin- tillator Tile	Deviation of overall mean: 18.4
99% (90%)	±20%
97% (84%)	±10%
88% (73%)	±5%





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Bottom Dimple

Part of the Scin- tillator Tile	Deviation of overall mean: 14.5
99.8% (90%)	±15%
96% (82%)	±10%
83% (69%)	±5%





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Summary and Outlook

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Timing of the Tile Signal

Observe directly: Significantly faster tile signal for direct coupling

Tile Uniformity Study

- SiPM Integration: Tight cell mounting, higher light yield, easy SiPM alignment
- Side Dimple: High Uniformity, easy design, scalable for 5 mm and 3 mm tiles
- NEW: Bottom Dimple: Only possible with very small casing
 → MPPC P-Series available as SMD type
 Avoids signal drop at coupling pos while keeping light yield high
 → Potential for perfect uniformity
 <u>Further improvements under investigation!
 Test concept for 3 mm tiles!

 </u>



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	Appendix



Signal of Tile & Coincidence Cube simultaneously > 3 p.e.



Tile Coupling

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Coupling Properties

SiPM:	MPPC25, 1600 Pix, 2 plastic casings
Scintillator:	Saint Gobain BC-420
Tile Size:	$3 \times 3 \times 0.5$ and $3 \times 3 \times 0.3$ cm ³
Tile Surface:	Polished, completely enclosed by 3M mirror foil
SiPM Coupling:	Direct (Air Gap) fiberless coupling
Coupling Pos:	Center of one side face





Quantification of the Uniformity with Area Fractions

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Appendix



Determination of the Area Fractions

• Define the Tile Position (fixed to $3 \times 3 \text{ cm}^2$):

 \rightarrow Note: Measurement unprecise at tile edges Reason: Finite iris size of source casing \rightarrow conelike e^- emission

- Determine OMSH: Mean value of all measurement points outside the extreme regions
- Determine Area Fractions: Fraction of all on-tile measurement points lying within a certain deviation region around the OMSH



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Distortion of the cell signal distribution

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Distortion of the energy sum distribution of showers \Rightarrow Effect on energy reconstruction process

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Deterioration of the energy resolution increasing with the particle energy